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CCS L 56



**NATIONAL STANDARD OF THE
PEOPLE'S REPUBLIC OF CHINA**

GB/T 17865-1999

**Specification for measuring depth of focus and best focus
(English Translation)**

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What this standard covers

This standard specifies the focus and coke used in the production of integrated circuit lithography techniques and their close deep measurement problems.

Document data

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Standards quoted by this document

GB/T 16878-1997; SJ/T 10584-1994